



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	Fukuda et al.) Group Art Unit 1763
)
Appl. No. :	09/511,934)
)
Filed :	February 24, 2000)
)
For :	THIN-FILM FORMING) APPARATUS HAVING AN) AUTOMATIC CLEANING) FUNCTION FOR CLEANING) THE INSIDE))
)
Examiner :	R. Kackar)

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AMENDMENT AND RESPONSE TO ADVISORY ACTION

#12C
 11/5/02
 MW

Assistant Commissioner for Patents

Washington, D.C. 20231

Dear Sir:

A request for continued examination (RCE) has been filed under 37 C.F.R. § 1.114 in the above-identified application. In response to the Advisory Action mailed October 2, 2002, please enter the AMENDMENT AFTER FINAL dated September 18, 2002, and further amend the above-captioned application as follows:

IN THE CLAIMS:

Please cancel Claims 2-3 and 11-20 without prejudice.

Please amend Claim 1 as follows:

1. (Thrice amended) A thin film forming apparatus comprising:

a reaction chamber for forming at a film formation temperature a thin film on a workpiece placed on a susceptor provided in the reaction chamber, said susceptor being made of aluminum nitride and provided with a heater for heating the workpiece, said reaction chamber being